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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Zhang

Application No: 10/743,963

Filed: December 22, 2003

For: CHEMICAL MECHANICAL PLANARIZATION  
 (CMP) SYSTEM AND METHOD FOR PREPARING  
A WAFER IN A CLEANING MODULE



Attorney Docket No: LAM2P456

Examiner: RACHUBA, M.

Group Art Unit: 3723

Date: February 3, 2006

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on February 3, 2006.

Signed:

Michael L. Gencarella

Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application. The fee has been calculated as shown below.

	<u>Claims Remaining After Amendment</u>	<u>Highest Previously Paid For</u>	<u>Present Extra</u>	<u>SMALL ENTITY RATE FEE</u>	<u>OR</u>	<u>LARGE ENTITY RATE FEE</u>
TOTAL CLAIMS	<u>9</u> -	<u>22</u>	<u>00</u>	X25 = \$	OR	X50 = \$
INDEP CLAIMS	<u>1</u> -	<u>04</u>	<u>00</u>	X100 = \$	OR	X200 = \$
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$180	X360	\$
			TOTAL	\$ _____		\$ _____

- Applicant(s) hereby petition for a month(s) extension of time to respond to the outstanding Office Action. Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805 (Order No. LAM2P456).
- Enclosed is our Check No. in the amount of to cover the additional claim fee and/or extension of time fees.
- If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P456). A copy of this sheet is enclosed.

Respectfully submitted,  
 MARTINE PENILLA & GENCARELLA, LLP

Michael L. Gencarella, Esq.  
 Registration No. 44,703



**PATENT**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of )  
Xiuhua Zhang ) Examiner: Rachuba, Maurina  
Application No. 10/743,963 ) Art Unit: 3723  
Filed: December 22, 2003 ) Docket No. LAM2P456  
For: CHEMICAL MECHANICAL PLANARIZATION ) Date: February 03, 2006  
(CMP) SYSTEM AND METHOD FOR PREPARING )  
A WAFER IN A CLEANING MODULE )

**CERTIFICATE OF EXPRESS MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service on **February 03, 2006**, in an envelope as first class mail, addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed:   
Michael L. Gencarella

**AMENDMENT**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office action dated November 3, 2005, please enter the following amendments and remarks.

**Amendments to the claims** are reflected in the listing of claims, which begin on page 2 of this paper.

**Remarks/Arguments** begin on page 4 of this paper.